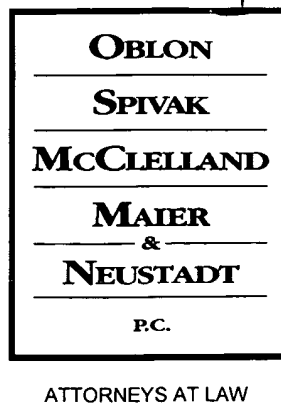




Docket No.: 243476US26YA

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313



RE: Application Serial No.: 10/673,375
Applicants: Anthony DIP, et al.
Filing Date: September 30, 2003
For: DEPOSITION OF SILICON-CONTAINING FILMS
FROM HEXACHLORODISILANE
Group Art Unit: 2813
Examiner: HARRISON, M. D.

SIR:

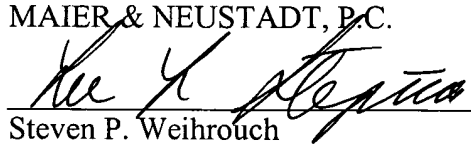
Attached hereto for filing are the following papers:

Response to Restriction Requirement

Our check in the amount of **\$0.00** is attached covering any required fees. In the event any variance exists between the amount enclosed and the Patent Office charges for filing the above-noted documents, including any fees required under 37 C.F.R. 1.136 for any necessary Extension of Time to make the filing of the attached documents timely, please charge or credit the difference to our Deposit Account No. 15-0030. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. 1.136 for the necessary extension of time. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.



Steven P. Weihrouch

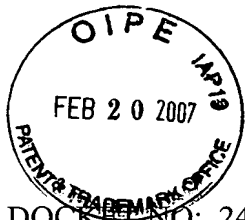
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Lee L. Stepina
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DOCKET NO: 243476US26YA

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :
ANTHONY DIP, ET AL. : EXAMINER: HARRISON, MONICA D.
SERIAL NO: 10/673,375 :
FILED: SEPTEMBER 30, 2003 : GROUP ART UNIT: 2813
FOR: DEPOSITION OF SILICON- :
CONTAINING FILMS FROM
HEXACHLORODISILANE

RESPONSE TO RESTRICTION REQUIREMENT

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

In response to the Restriction Requirement dated January 18, 2007, Applicants provisionally elect, *with traverse*, Group I, Claims 1-20, 23-37, 47 and 49, listed in the Restriction Requirement as drawn to methods of depositing a silicon-containing film on a substrate, and Applicants list Claims 1-20, 23-37, 47 and 49, as readable thereon.

Applicants respectfully traverse the Restriction Requirement for the following reason.

MPEP § 803 states:

If the search and examination of an entire application can be made without serious burden, the Examiner must examine it on the merits, even though it includes claims to distinct or independent inventions.

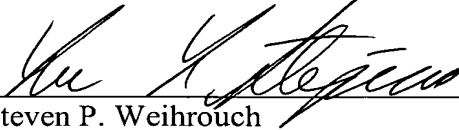
The claims of the present invention would appear to be part of an overlapping search area. Accordingly, Applicants respectfully traverse the outstanding Restriction Requirement on the grounds that a search and examination of the entire application would not place a

Application No. 10/673,375
Reply to Restriction Requirement of January 18, 2007

serious burden on the Examiner. Therefore, an action on all of the Claims 1-20, 23-37, 38-47, and 49 is earnestly solicited.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.



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